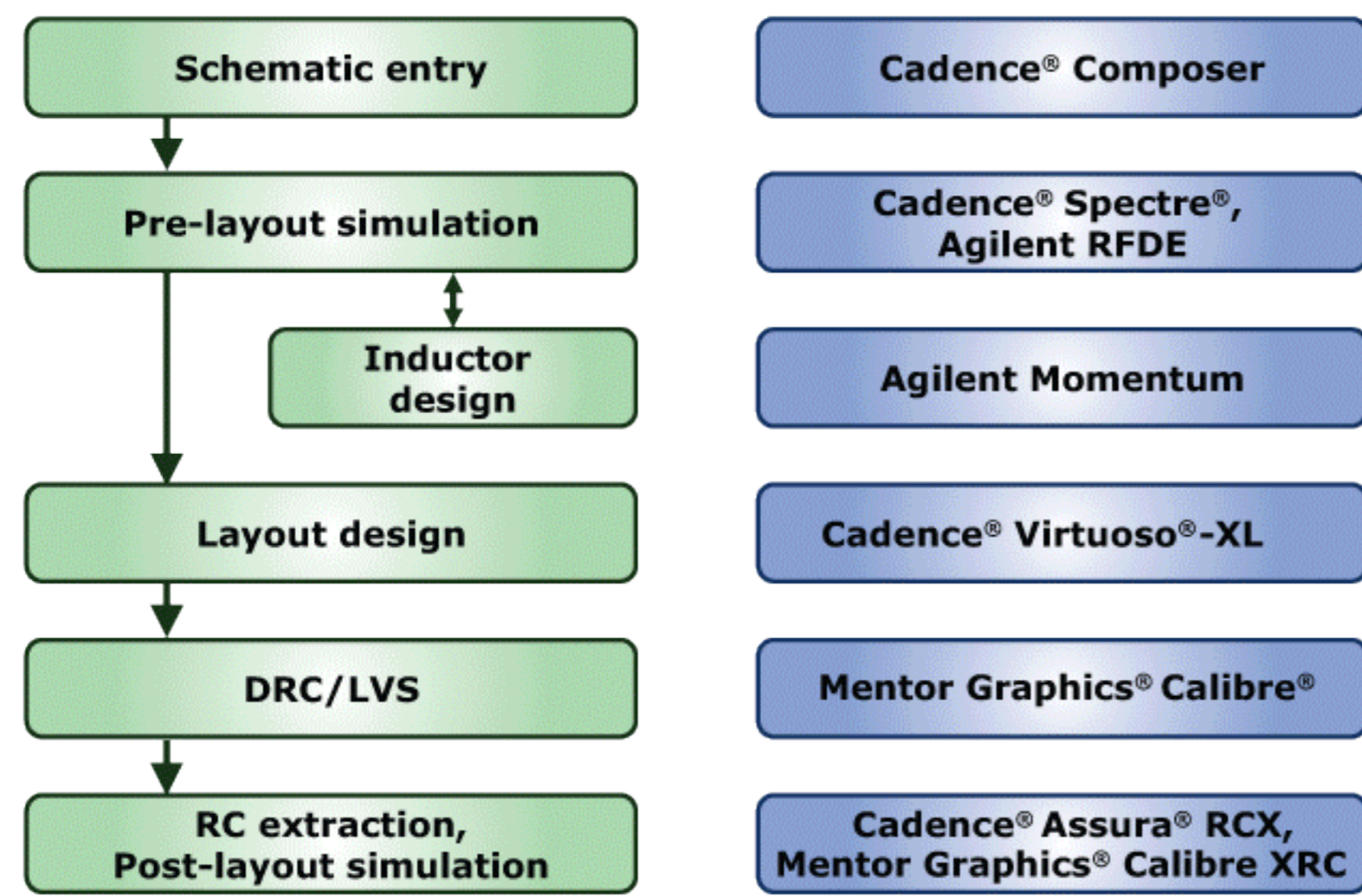


### RFCMOS TECHNOLOGY OVERVIEW

Technology Node	130nm	90nm	65nm	40nm
V <sub>dd</sub> [V]	1.5 1.2	1.2 1.0	1.2 1.0	1.1 0.9
F <sub>t</sub> [GHz]	90	140	180	~250
Random Logic Density [kgates/sqmm]	206	403	800	2100
6 - tr SRAM Cell Density [squm/bit]	2,5	1,25	0,495	0,24

- > Using standard CMOS Process
- > Selective mixed-signal options
- > Multi V<sub>th</sub>, deep-N-well, High/Low-resistive Poly-Silicon, thick metal layers, MIM.cap., ..

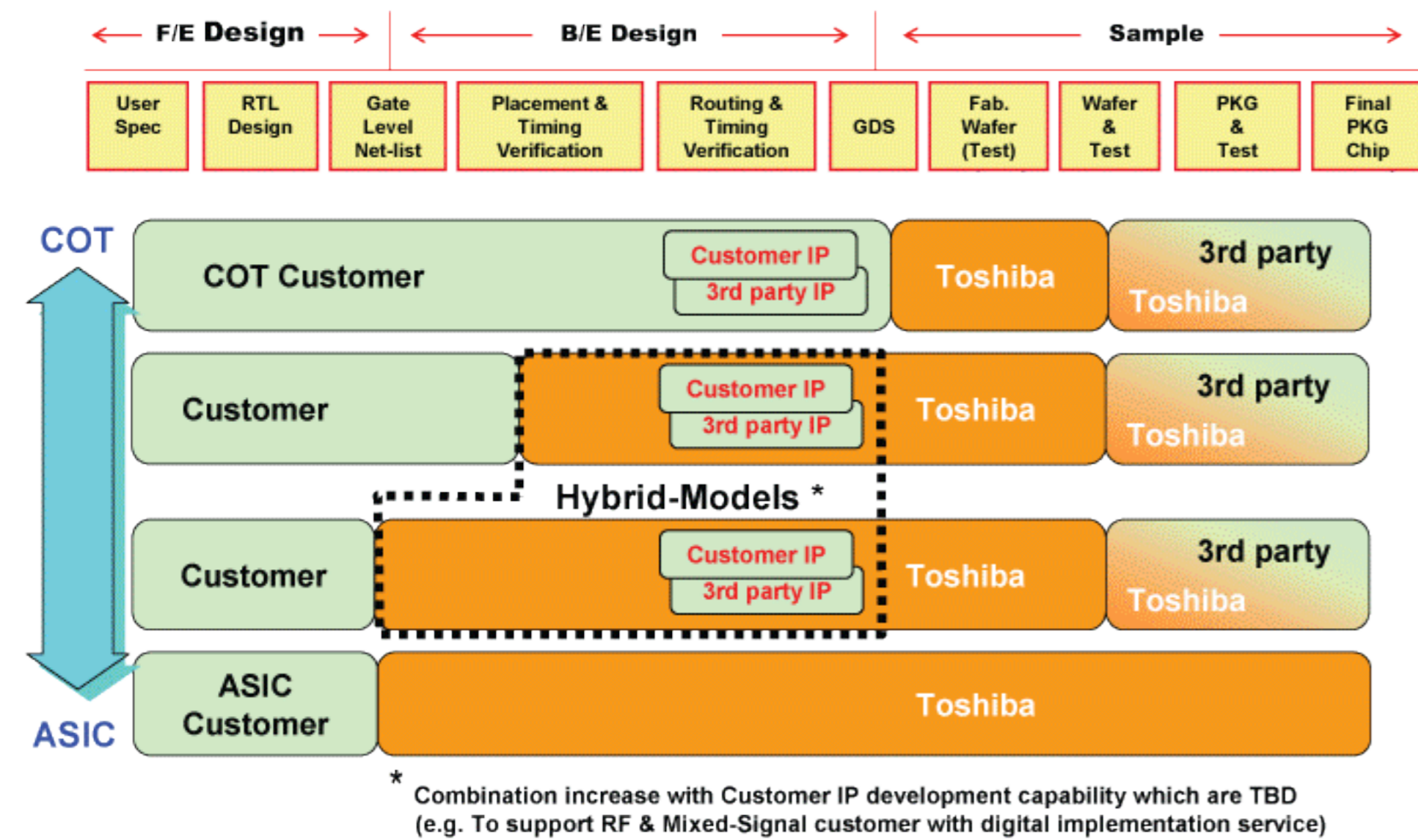


### RF-PDK (PROCESS DESIGN KIT)

- > MS- and RF- models are based on the same devices
- > RF models additionally consider RF behaviour
- > RF-PDK contains additional RF components Inductor (scalable pcell and model)
- > Fully verified on silicon

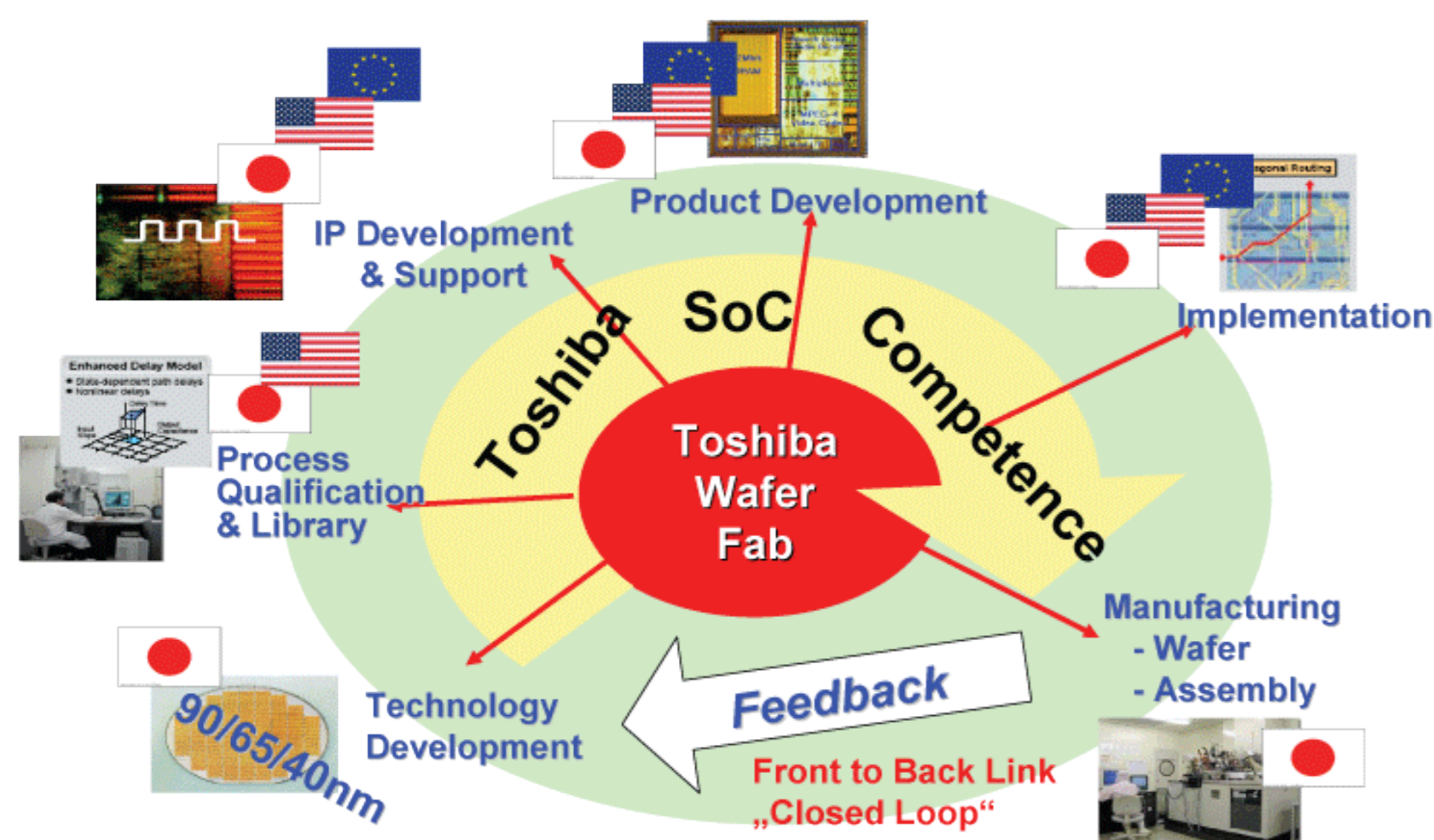
### SUPPORTED EDA ENVIRONMENT

- > Industry standard tools from leading vendors like Cadence, Mentor and Agilent are supported by Toshiba's RF-CMOS PDKs
- > Support for other tools is available on request



### HYBRID ASIC/COT MODELS

- > Flexible I/F's
- > Flexible Design-in
- > Flexible Product-out
- > Cost model tbd. ASIC or foundry



### ADVANCED OPEN IDM MODEL

#### (BUSINESS STRATEGY FOR ASIC & FOUNDRY)

- > All in One Hand
- > All from One Source
- > One Partner
- > Road-map to 28/20nm